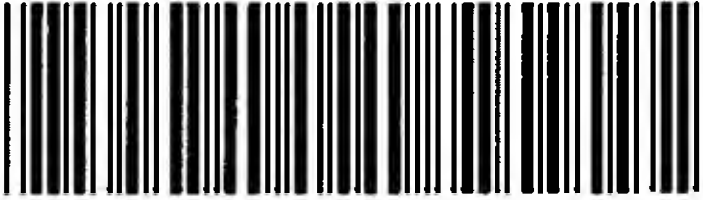


<div>Search Notes</div> <div></div>	Application/Control No.	Applicant(s)/Patent under Reexamination	
	10/626,744	YAMAMOTO ET AL.	
	Examiner	Art Unit	
	ALI ALLAWI	2877	

SEARCHED			
Class	Subclass	Date	Examiner

INTERFERENCE SEARCHED			
Class	Subclass	Date	Examiner

SEARCH NOTES (INCLUDING SEARCH STRATEGY)		
	DATE	EXMR
Searched 250/461.1 radiant energy with ultraviolet source	11/10/2005	AA
Searched 356/446,447 for light reflection and diffusion	11/10/2005	AA
Consulted with primaries Smith and Coleman on scope and overview of the invention and key word search	11/10/2005	AA
Key word search included radiant energy, plasma source, euv, reflection, diffusion, wafer etching, semiconductor, photoresist	11/10/2005	AA
deposition and deposition measurement and sensing was also searched, see east history for details	11/10/2005	AA